

REMARKS/ARGUMENTS

Claims 1, 2 and 6-10 are amended. Claims 3-5 and 11-16 are canceled. Claim 1, 2 and 6-10 are pending.

The disclosure is objected as not referencing co-pending applications. Applicant has reviewed its pending patent portfolio and notes that applications 10/042,879; 10/324,643; 10/612,383; and 11/118,022 all relate to oxidation of semiconductor devices and are assigned to the same assignee. However, these applications do not appear to be related to the same subject matter and therefore have not previously been identified to the Examiner. Reconsideration of the objection to the specification is respectfully requested.

Claims 1-10 are rejected under 35 U.S.C. §102 as being anticipated by U.S. Patent No. 5,364,007 to Jacobs et al. ("Jacobs"). Claims 1-10 are also rejected under 35 U.S.C. §102 as being anticipated by U.S. Patent No. 6,866,182 to Wong et al. ("Wong"). Reconsideration of the application in light of the remarks below is respectfully requested.

Among the limitations of independent claim 1, which are neither disclosed nor suggested in the art of record are:

- A. a holding device for securing the semiconductor device to a platform
- B. the cover defining a hollow cavity located adjacent to the opening; and
- C. a gas inlet in fluid communication with the cavity and the opening for supplying a relatively inert gas.

Focusing first on the Jacobs reference, the Examiner points to heating chamber 14 as corresponding to element A. However, heating chamber 14 is used to heat a semiconductor

device and there is no disclosure in Jacobs for this heating element being used to secure a semiconductor device to a platform as is claimed. See, for example, Column 8, lines 40-47; Column 9, lines 7-10 of Jacobs.

With respect to limitation B, the Examiner points to gas knife 58 in Jacobs. However, cavity 58 is not located “adjacent” to opening 16 – as is claimed. Moreover, as set forth in limitation C in Jacobs, there is no gas inlet in fluid communication with gas knife 58 and opening 16 - as is claimed. Therefore, it is asserted that independent claim 1 is patentable over the Jacobs reference.

With respect to Wong, Wong does not show a hollow cavity located adjacent to an opening as set forth in limitation B above. The Examiner points to elements 10 and 18 in Fig. 4 of Wong as showing these limitations. However, a careful reading of Wong shows that element 18 is a “porous material” and is not “hollow” as is claimed. Therefore, it is asserted that independent claim 1 is patentable over Wong.

Dependent claims 2 and 6-10 are dependent on independent claim 1 and include additional recitations which, when combined with the limitations of independent claim 1, are also neither disclosed nor suggested in either the Jacobs or Wong references. It is asserted that

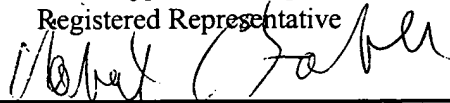
these claims are patentable as well. Reconsideration of the rejection of claims 1, 2 and 6-10

under 35 U.S.C. §102 is respectfully requested in light of the remarks above.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on March 27, 2006:

Robert C. Faber

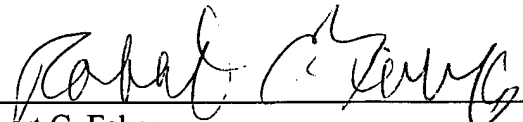
Name of applicant, assignee or
Registered Representative


Signature

March 27, 2006

Date of Signature

Respectfully submitted,


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